

ASMMC.036AUS



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT

H21/Response

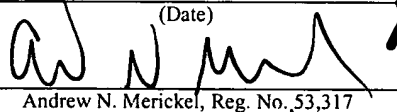
Applicant : Sophie et al.
Appl. No. : 09/975,466
Filed : October 9, 2001
For : IN SITU REDUCTION OF
COPPER OXIDE PRIOR TO
SILICON CARBIDE
DEPOSITION
Examiner : Kjielin
Group Art Unit : 2813

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

October 10, 2003

(Date)

Adm H
10/23/03

Andrew N. Merickel, Reg. No. 53,317

Response to Office Action

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The present paper is submitted in response to the Office Action mailed on July 11, 2003.
Applicants respectfully request consideration of the Remarks beginning on page 2 of this paper.

RECEIVED
OCT 17 2003
TECHNOLOGY CENTER 2800